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APPLICATION NO).	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
10/631,087		07/31/2003	Jonathan Jay Bernstein	MA03-004	2028
31362	7590	06/20/2005		EXAM	INER
JOANNE	N. PAPP	AS	CHOI, WILLIAM C		
45 NAGO				ART UNIT PAPER NUMBER	
ACTON,	MA 0172	20		TALER NOMBER	
				2873	
			DATE MAILED, 06/20/2005		

Please find below and/or attached an Office communication concerning this application or proceeding.

		V2					
	Application No.	Applicant(s)					
Office Action Comment	10/631,087	BERNSTEIN ET AL.					
Office Action Summary	Examiner	Art Unit					
The MAILING DATE of this communication com	William C. Choi	2873					
The MAILING DATE of this communication app Period for Reply	ears on the cover sheet with the c	orrespondence address					
A SHORTENED STATUTORY PERIOD FOR REPLY THE MAILING DATE OF THIS COMMUNICATION. - Extensions of time may be available under the provisions of 37 CFR 1.13 after SIX (6) MONTHS from the mailing date of this communication. - If the period for reply specified above is less than thirty (30) days, a reply - If NO period for reply is specified above, the maximum statutory period w - Failure to reply within the set or extended period for reply will, by statute, Any reply received by the Office later than three months after the mailing earned patent term adjustment. See 37 CFR 1.704(b).	86(a). In no event, however, may a reply be time within the statutory minimum of thirty (30) days will apply and will expire SIX (6) MONTHS from cause the application to become ABANDONE	ely filed s will be considered timely. the mailing date of this communication. O (35 U.S.C. § 133).					
Status							
2a) ☐ This action is FINAL . 2b) ☑ This 3) ☐ Since this application is in condition for allowar	,—						
Disposition of Claims							
 5) ☐ Claim(s) is/are allowed. 6) ☒ Claim(s) <u>1,2,4-9,14 and 19</u> is/are rejected. 7) ☒ Claim(s) <u>3,10-13,15-18,20</u> is/are objected to. 	4a) Of the above claim(s) is/are withdrawn from consideration. 5) ☐ Claim(s) is/are allowed. 6) ☐ Claim(s) 1,2,4-9,14 and 19 is/are rejected. 7) ☐ Claim(s) 3,10-13,15-18,20 is/are objected to.						
Application Papers							
9) ☐ The specification is objected to by the Examine 10) ☑ The drawing(s) filed on 17 January 2005 is/are: Applicant may not request that any objection to the a Replacement drawing sheet(s) including the correction 11) ☐ The oath or declaration is objected to by the Ex	a)⊠ accepted or b)⊡ objected drawing(s) be held in abeyance. See ion is required if the drawing(s) is obj	e 37 CFR 1.85(a). ected to. See 37 CFR 1.121(d).					
Priority under 35 U.S.C. § 119							
12) Acknowledgment is made of a claim for foreign a) All b) Some * c) None of: 1. Certified copies of the priority documents 2. Certified copies of the priority documents 3. Copies of the certified copies of the prior application from the International Bureau * See the attached detailed Office action for a list	s have been received. s have been received in Applicati ity documents have been receive ı (PCT Rule 17.2(a)).	on No ed in this National Stage					
Attachment(s) 1) Notice of References Cited (PTO-892) 2) Notice of Draftsperson's Patent Drawing Review (PTO-948) 3) Information Disclosure Statement(s) (PTO-1449 or PTO/SB/08) Paper No(s)/Mail Date 0405.	4) Interview Summary Paper No(s)/Mail Da 5) Notice of Informal P 6) Other:						

DETAILED ACTION

Allowable Subject Matter

The indicated allowability of claims 1-15 and 17-20 is withdrawn in view of the newly discovered reference(s) to Moon et al (U.S. 2003/0095307 A1). Rejections based on the newly cited reference(s) follow.

Information Disclosure Statement

Receipt of the Information Disclosure Statement (IDS) with copies of the references cited therein, was received on 4/18/2005. An initialized copy of the IDS is enclosed with this office action.

Claim Objections

Claim 1 is objected to because of the following informalities: in line 4, a "," should be inserted after "mirrors". Appropriate correction is required.

Claim Rejections - 35 USC § 102

The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless -

(e) the invention was described in (1) an application for patent, published under section 122(b), by another filed in the United States before the invention by the applicant for patent or (2) a patent granted on an application for patent by another filed in the United States before the invention by the applicant for patent, except that an international application filed under the treaty defined in section 351(a) shall have the effects for purposes of this subsection of an application filed in the United States

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only if the international application designated the United States and was published under Article 21(2) of such treaty in the English language.

Claims 1, 2, 4-9, 14 and 19 are rejected under 35 U.S.C. 102(e) as being anticipated by Moon et al.

In regard to claim 1, Moon et al discloses a spatial light modulator system comprising: a high fill factor MEMS array of tilting mirrors used to attenuate a plurality of wavelength channels in an optical network (page 5, sections [0093] & [0094], Figure 3); and an interface control circuit controlling said array of tilting mirrors (page 5, section [0093], lines 3-5, Figure 3, "90"), said interface circuit receiving and storing control signals to reconfigure wavelength channel definitions (pages 5 & 6, section [0094]).

Regarding claim 2, Moon et al discloses wherein said control circuit and said array of mirrors are fabricated on the same monolithic substrate (page 7, section [0108], lines 1-7 & 17-27, Figure 11).

Regarding claim 4, Moon et al discloses wherein said control signals further comprise definitions for the extent of each of said plurality of wavelength channels (page 4, sections [0081] & [0082] and pages 5 & 6, section [0094]).

Regarding claim 5, Moon et al discloses wherein the control signals further comprise a desired attenuation within each of said plurality of wavelength channels (page 4, sections [0081] & [0082] and pages 5 & 6, section [0094]).

Regarding claim 6, Moon et al discloses wherein said MEMS array is linear (Figure 3).

Regarding claim 7, Moon et al discloses wherein said high fill factor is greater than or equal to 90% (page 5, section [0091], lines 4-6).

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Regarding claim 8, Moon et al discloses wherein each mirror in said MEMS array of tilting mirrors further comprises a single tilting cantilever supported by two flexures (Figure 11, "Hinge").

Regarding claim 9, Moon et al discloses wherein each mirror has at least one actuation electrode (page 7, section [0108], lines 10-13, Figure 11)

Regarding claim 14, Moon et al discloses wherein each mirror in said MEMS array of tilting mirrors is supported by symmetrically located flexures whose rotational axis passes through the center of gravity of the mirror (Figure 11, "Hinge" & Figure 12, "205").

Regarding claim 19, Moon et al discloses wherein each of said MEMS mirrors is fabricated of a metal layer (page 7, section [0108], lines 7-8, Figure 11, "204")

Allowable Subject Matter

Claims 3, 10-13, 15-18 and 20 are objected to as being dependent upon a rejected base claim, but would be allowable if rewritten in independent form including all of the limitations of the base claim and any intervening claims.

The following is a statement of reasons for the indication of allowable subject matter: The prior art fails to teach a combination of all the claimed features as presented in claim 3: a spatial light modulator system comprising a MEMS array of tilting mirrors and an interface control circuit as claimed, specifically wherein said control circuit and said array of mirrors are not fabricated on the same monolithic substrate.

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The prior art fails to teach a combination of all the claimed features as presented in claims 10 and 11: a spatial light modulator system comprising a MEMS array of tilting mirrors and an interface control circuit as claimed, specifically wherein each mirror in said MEMS array comprises a single tilting cantilever with an asymmetric flexure resulting in 2-axis rotation.

The prior art fails to teach a combination of all the claimed features as presented in claim 12 and 13: a spatial light modulator system comprising a MEMS array of tilting mirrors and an interface control circuit as claimed, specifically wherein each mirror in said MEMS array is supported by side support flexures whose rotational axis is offset from the center of gravity of the mirror.

The prior art fails to teach a combination of all the claimed features as presented in claim 15: a spatial light modulator system comprising a MEMS array of tilting mirrors supported by symmetrically located flexures and an interface control circuit as claimed, specifically wherein each mirror further comprises a means for providing strain relief.

The prior art fails to teach a combination of all the claimed features as presented in claim 16: a spatial light modulator system comprising a MEMS array of tilting mirrors and an interface control circuit as claimed, specifically wherein each mirror has at least one landing electrode having a same potential as said mirror.

The prior art fails to teach a combination of all the claimed features as presented in claims 17 and 18: a spatial light modulator system comprising a MEMS array of tilting mirrors and an interface control circuit as claimed, specifically wherein each mirror in said MEMS array further comprises means for maintaining mirror flatness.

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The prior art fails to teach a combination of all the claimed features as presented in claim 20: a spatial light modulator system comprising a MEMS array of tilting mirrors and an interface control circuit as claimed, specifically wherein said mirror layer is polished flat using a CMP (Chemical Mechanical Planarization) Technique.

Conclusion

Any inquiry concerning this communication or earlier communications from the examiner should be directed to William C. Choi whose telephone number is (571) 272-2324. The examiner can normally be reached on Monday-Friday from about 9:00 am to 6 pm.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Georgia Y. Epps can be reached on (571) 272-2328. The fax phone number for the organization where this application or proceeding is assigned is 703-872-9306.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

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WC. William Choi Patent Examiner Art Unit 2873 June 13, 2005

Georgia Epps
Supervisory Patent Examiner
Technology Center 2800

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